

# Lecture 01

## MEMS Syllabus, CO and PO

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# MEMS Syllabus



# MEMS - Credits, Examination Scheme and Course Prerequisite

Subject Code	Course Name	Teaching Scheme	Credits Assigned					
		Theory	Practical	Tutorial	Theory	TW/ Practical	Tutorial	Total
EXC803	MEMS Technology	04	--	--	04		--	04

Subject Code	Subject Name	Examination Scheme							
		Theory Marks				Term Work	Practical	Oral	Total
		Internal assessment			End Sem. Exam				
		Test 1	Test 2	Ave. Of Test 1 and Test 2					
EXC803	MEMS Technology	20	20	20	80	-	-	-	100

## Course Pre –requisite:

- EXC 404: Basic VLSI Design
- EXC 604: IC Technology

# MEMS - Syllabus

Module No.	Unit No.	Topics	Hrs.
1.		<b>Introduction to MEMS</b>	04
	1.1	Introduction to MEMS & Real world Sensor/Actuator examples (DMD, Air-bag, pressure sensors). MEMS Sensors in Internet of Things (IoT), BioMedical Applications	
2		<b>MEMS Materials and Their Properties</b>	10
	2.1	Materials (eg. Si, SiO <sub>2</sub> , SiN, Cr, Au, Ti, SU8, PMMA, Pt); Important properties: Young modulus, Poisson's ratio, density, piezoresistive coefficients, TCR, Thermal Conductivity, Material Structure. Understanding Selection of materials based on applications.	
3		<b>MEMS Fab Processes – 1</b>	11
	3.1	Understanding MEMS Processes & Process parameters for: Cleaning, Growth & Deposition, Ion Implantation & Diffusion, Annealing, Lithography. Understanding selection of Fab processes based on Applications	
4		<b>MEMS Fab Processes – 2</b>	10
	4.1	Understanding MEMS Processes & Process parameters for: Wet & Dry etching, Bulk & Surface Micromachining, Die, Wire & Wafer Bonding, Dicing, Packaging. Understanding selection of Fab processes based on Applications	
5		<b>MEMS Devices</b>	11
	5.1	Architecture, working and basic quantitative behaviour of Cantilevers, Microheaters, Accelerometers, Pressure Sensors, Micromirrors in DMD, Inkjet printer-head. Understanding steps involved in Fabricating above devices	
6		<b>MEMS Device Characterization</b>	06
	6.1	Piezoresistance, TCR, Stiffness, Adhesion, Vibration, Resonant frequency, & importance of these measurements in studying device behavior, MEMS Reliability	
<b>Total</b>			<b>52</b>

# MEMS - Recommended Books

## Recommended Books:

1. An Introduction to Microelectromechanical Systems Engineering; 2<sup>nd</sup> Ed - by N. Maluf, K Williams; Publisher: Artech House Inc
2. Practical MEMS - by Ville Kaajakari; Publisher: Small Gear Publishing
3. Microsystem Design - by S. Senturia; Publisher: Springer
4. Analysis and Design Principles of MEMS Devices - Minhang Bao; Publisher: Elsevier Science
5. Fundamentals of Microfabrication - by M. Madou; Publisher: CRC Press; 2 edition
6. Micro Electro Mechanical System Design - by J. Allen; Publisher: CRC Press
7. Micromachined Transducers Sourcebook - by G. Kovacs; Publisher: McGraw-Hill

# MEMS - Examination Scheme

**Internal Assessment (IA):**

Two tests must be conducted which should cover at least 80% of syllabus. The average marks of both the test will be considered as final IA marks

**End Semester Examination:**

1. Question paper will comprise of 6 questions, each of 20 marks.
2. Total 4 questions need to be solved.
3. Question No.1 will be compulsory and based on entire syllabus wherein sub questions of 2 to 5 marks will be asked.
4. Remaining questions will be selected from all the modules

# Course Objectives

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# MEMS - Course Objectives

**Course Objective:**

- To provide a basic knowledge of MEMS processing steps and processing modules.
- To demonstrate the use of semiconductor based processing modules used in the fabrication of variety of sensors and actuators (e.g. pressure sensors, accelerometers, etc.) at the micro-scale.
- To provide an understanding of basic design and operation of MEMS sensors and transducers.

# Program Outcome

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# MEMS - Program Outcome

Program Outcome	Description
<b>Pa</b>	an ability to apply knowledge of mathematics, science, and engineering principles
<b>Pb</b>	an ability to apply this knowledge of mathematics, science, and engineering principles to identify, formulate, and solve engineering problems,
<b>Pc</b>	an ability to design and conduct experiments, as well as to analyze and interpret data,
<b>Pd</b>	an ability to exhibit management principles and to function as a member of multidisciplinary teams
<b>Pe</b>	an ability to design a system, component, or process to meet desired needs within realistic constraints such as economic, environmental, social, political, ethical, health and safety, manufacturability, and sustainability,
<b>Pf</b>	a recognition of the need for
<b>Pg</b>	a knowledge of contemporary issues
<b>Ph</b>	an ability to use the techniques, skills, and modern engineering tools necessary for engineering practice,
<b>Pi</b>	the broad education necessary to understand the impact of engineering solutions in a global, economic, environmental, and societal context,
<b>Pj</b>	an understanding of professional and ethical responsibility,
<b>Pk</b>	an ability to communicate effectively, and
<b>Pl</b>	an ability to understand and expertise in various high-end and advanced computational and simulation software like MATLAB, Labview, Xilinx, Microwind, Qualnet etc.